ASMMC.9CP1DV1C1 PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Sherman

Appl. No. : 10/683,727

Filed : October 10, 2003

For : SEQUENTIAL CHEMICAL

VAPOR DEPOSITION

Examiner : Kelly M. Stouffer

Group Art Unit : 1762

Confirmation No.: 1627

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April 15, 2008

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Andrew N. Merickel, Reg. No. 53,317

AMENDMENT AND RESPONSE TO OFFICE ACTION

Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

The present paper is submitted in response to the final Office Action dated December 28, 2007 and is accompanied by a request for a one-month extension of time. Applicant appreciates the Examiner's willingness to consider the remarks herein in light of the interview conducted on February 23, 2008. The amendments simply cancel several claims and are believed to place the application in condition for allowance.

Amendments to the Claims begins on page 2 of this paper.

Summary of Interview begins on page 3 of this paper.

Remarks/Arguments begin on page 4 of this paper.